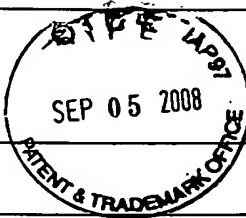


Form PTO-1449 (REV. 1/06)		US Dept. of Commerce PATENT & TRADEMARK OFFICE		ATTY DOCKET NO. 118039		APPLICATION NO. 10/733,454	
INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)							
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APPLICANT(S) Shigemi OHTSU et al.				FILING DATE December 12, 2003			
GROUP 1791							

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EXAMINER	DATE CONSIDERED
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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